

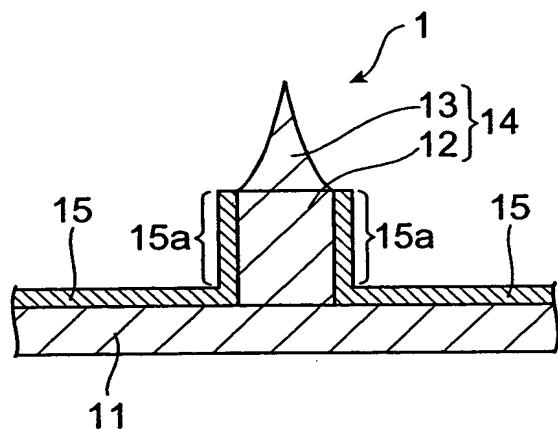
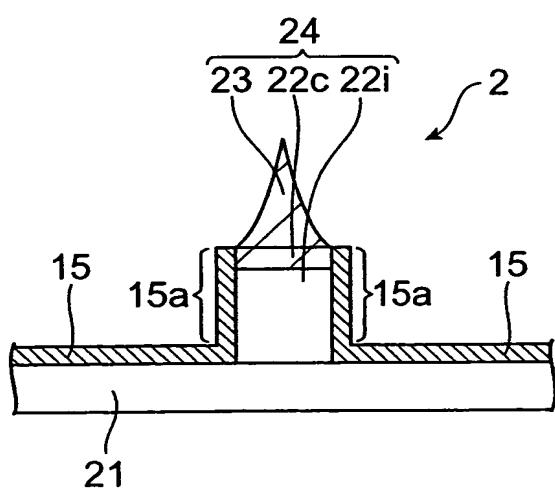
Fig. 1***Fig. 2***

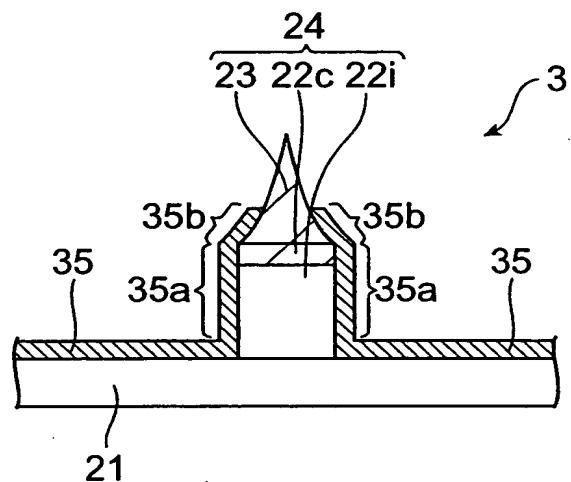
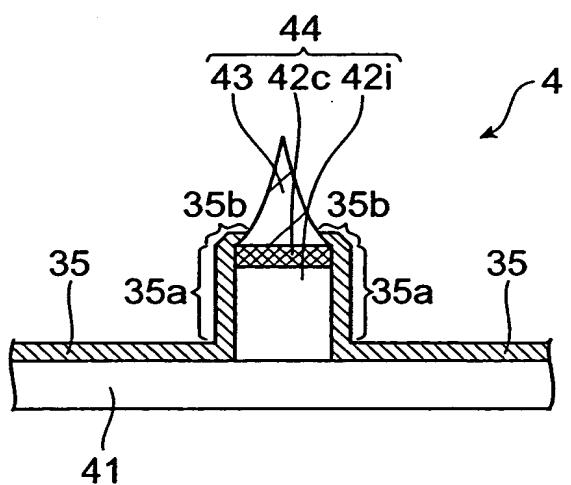
Fig.3**Fig.4**

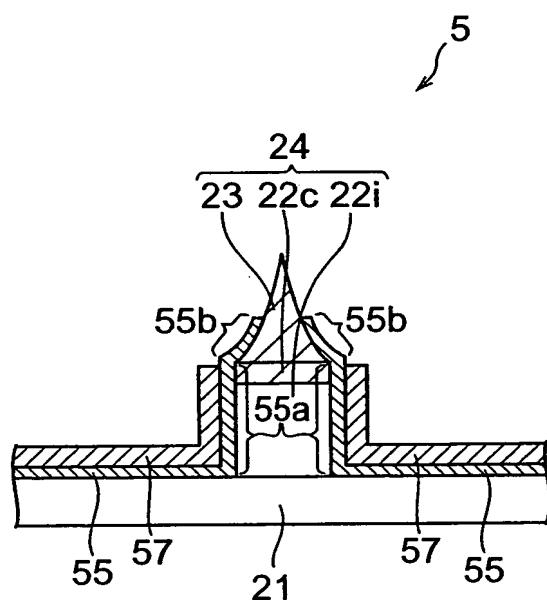
Fig.5

Fig.6A

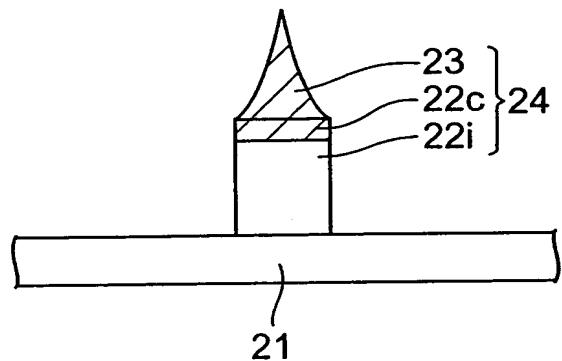


Fig.6B

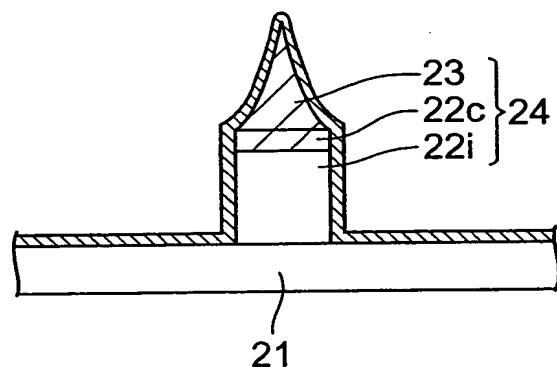
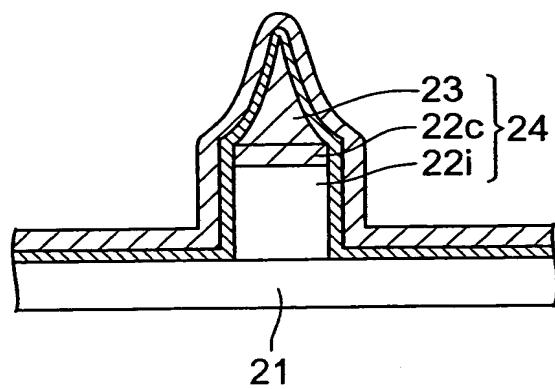


Fig.6C



5/18

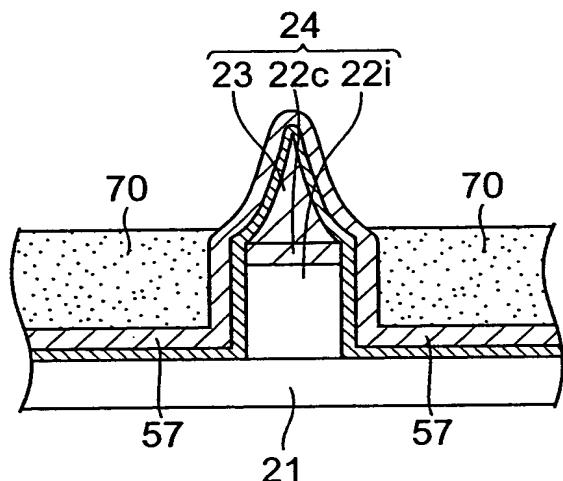
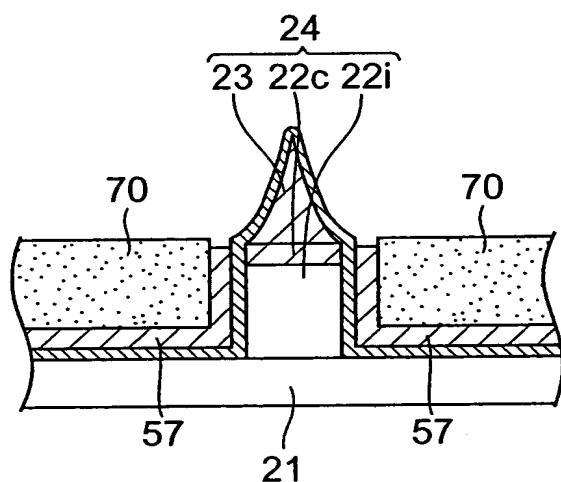
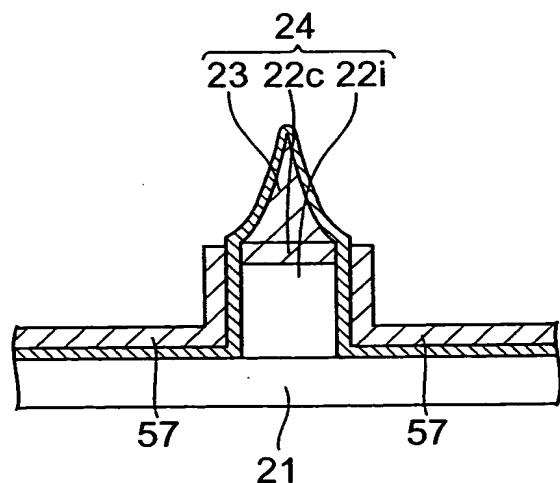
Fig.7A**Fig.7B****Fig.7C**

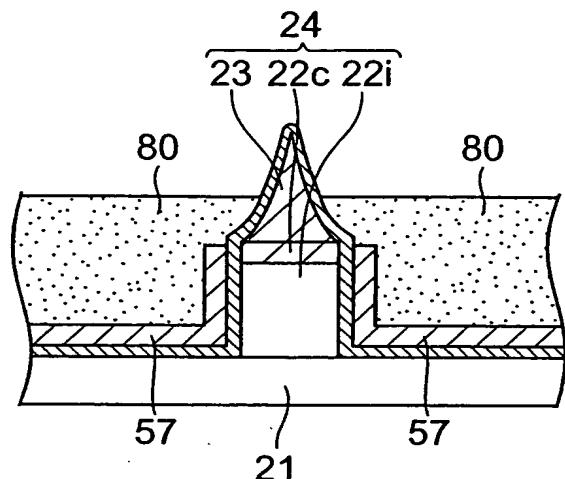
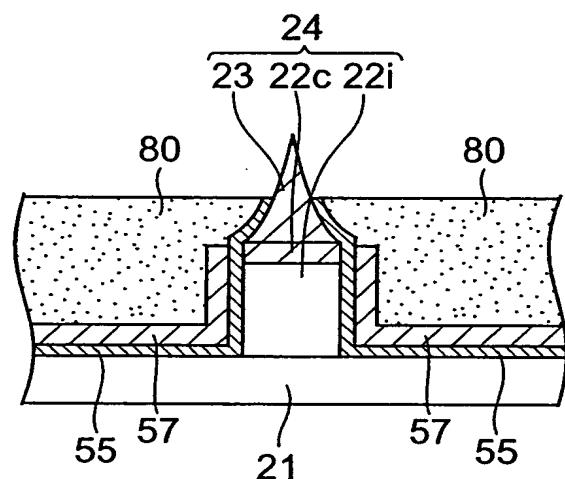
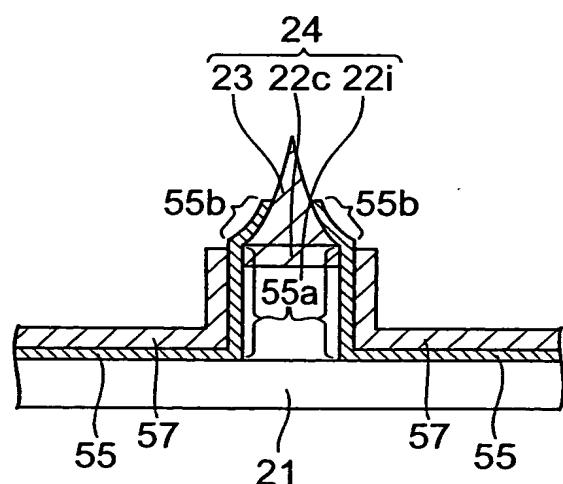
Fig.8A**Fig.8B****Fig.8C**

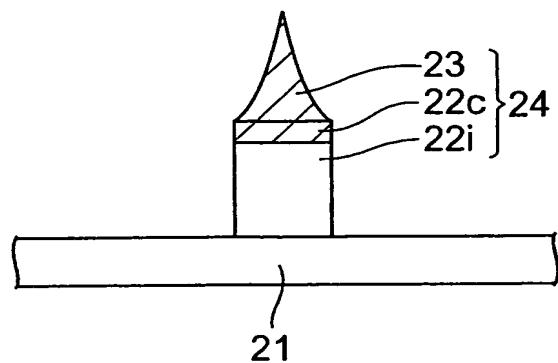
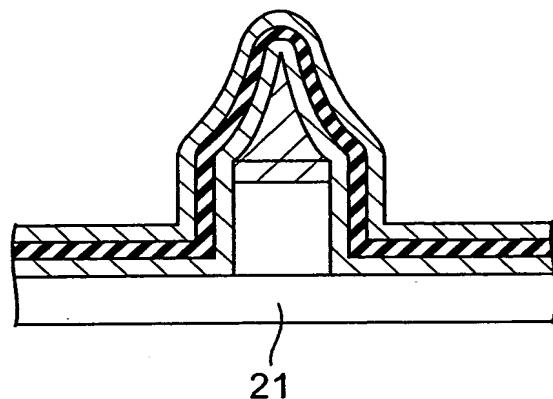
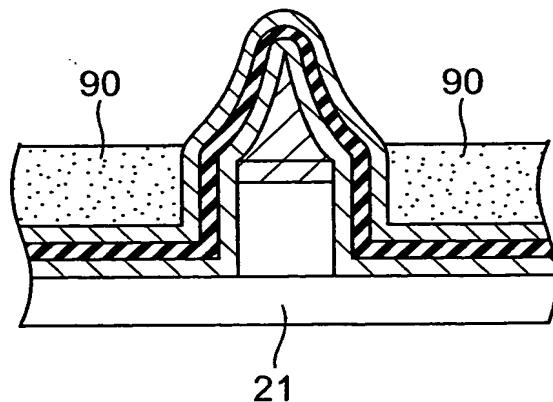
Fig.9A**Fig.9B****Fig.9C**

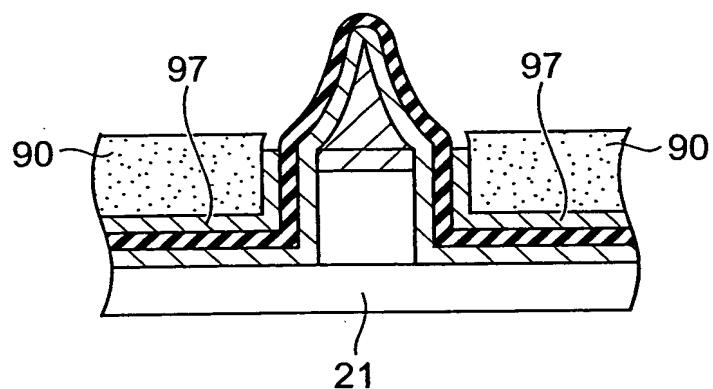
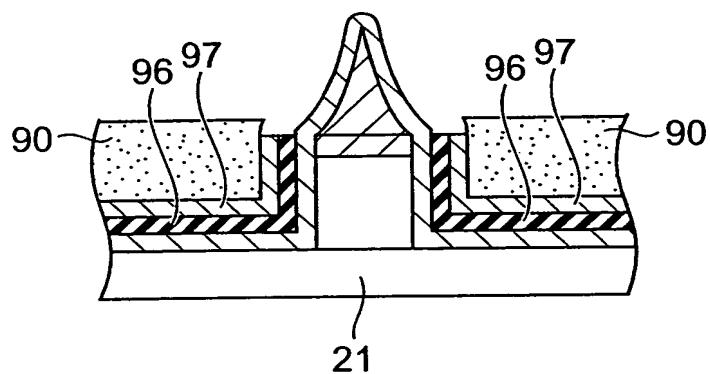
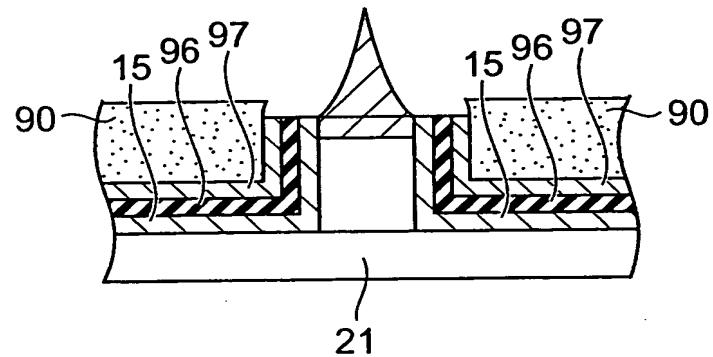
Fig.10A**Fig.10B****Fig.10C**

Fig.11

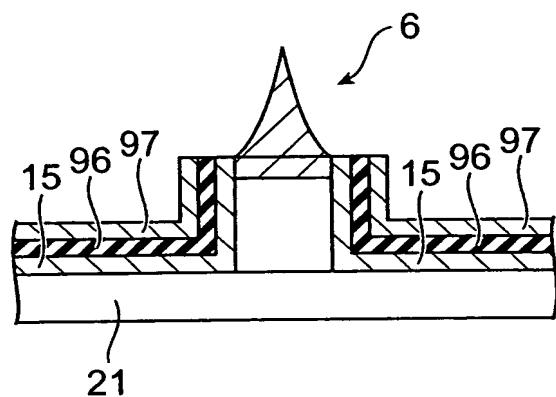
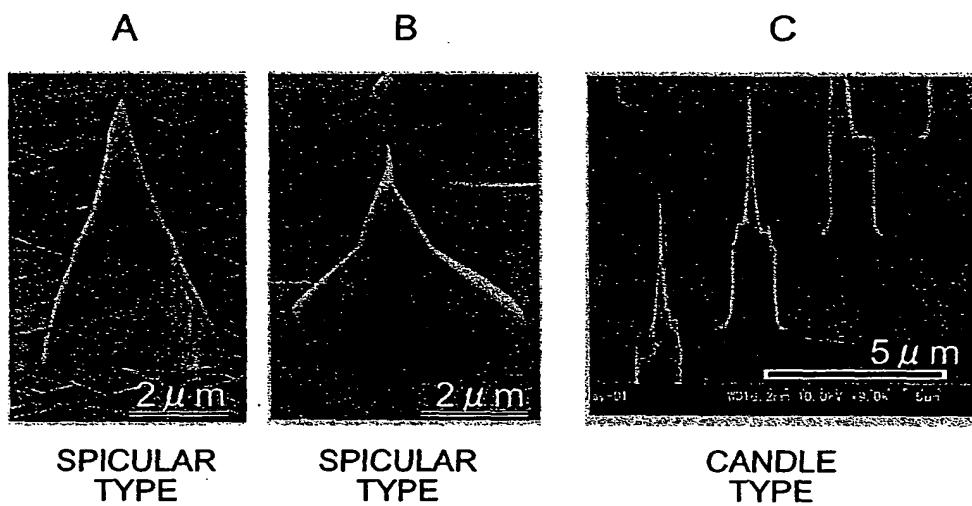


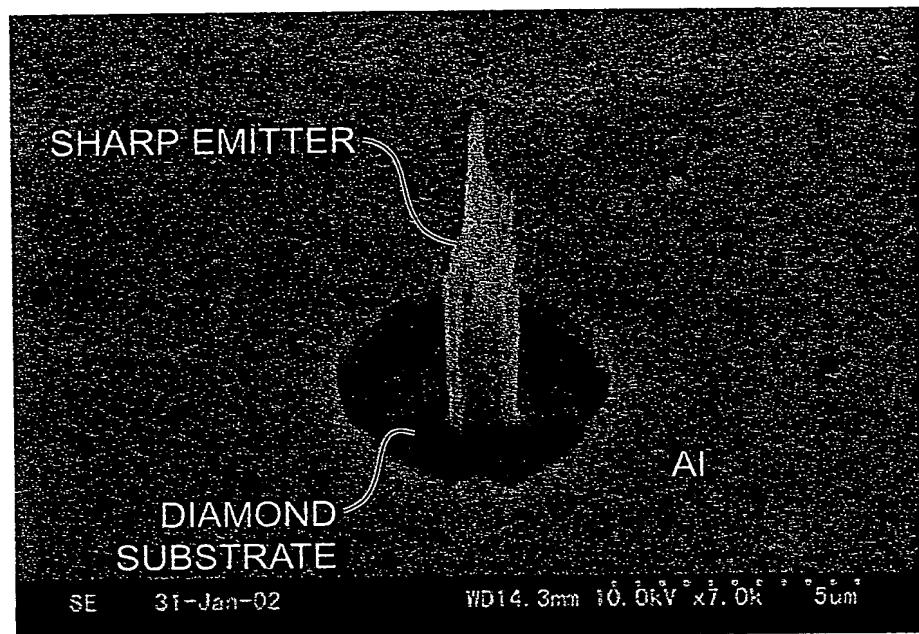
Fig.12



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11/18

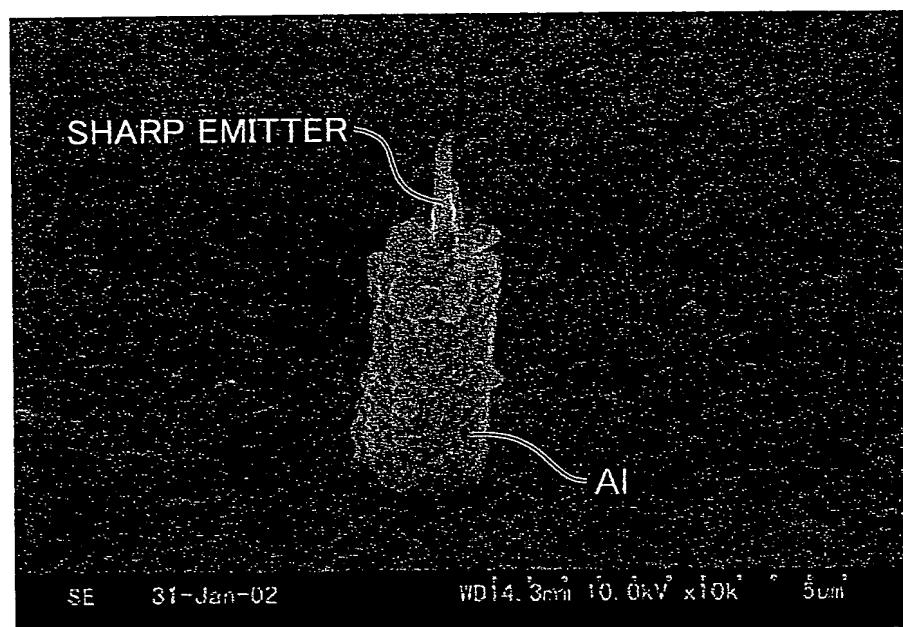
Fig.13



FP03-0161-00

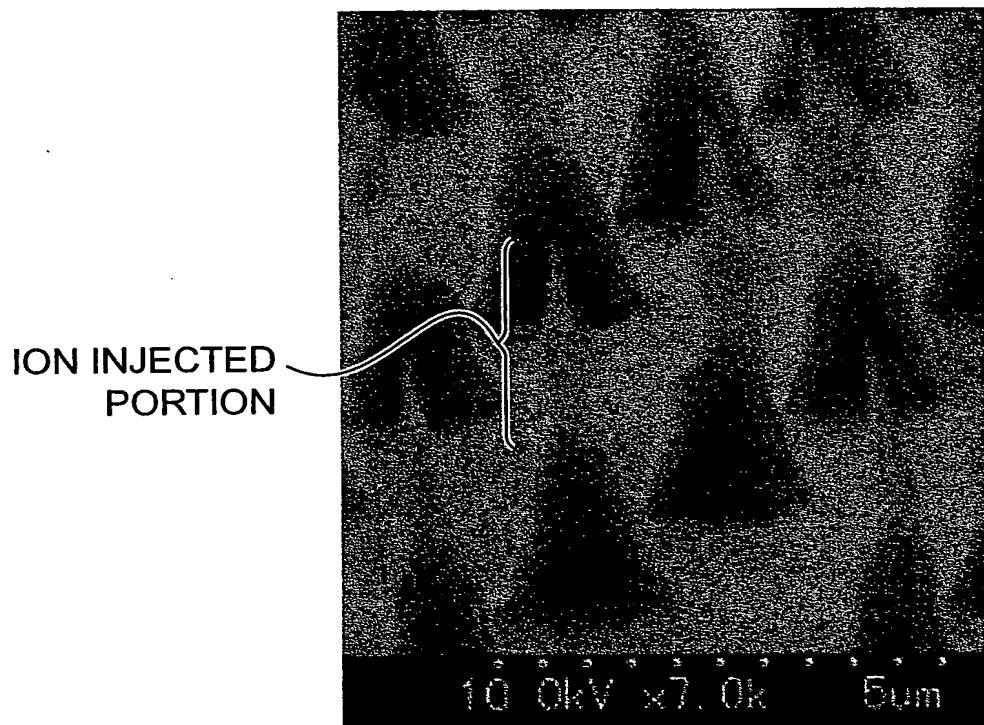
12/18

Fig.14



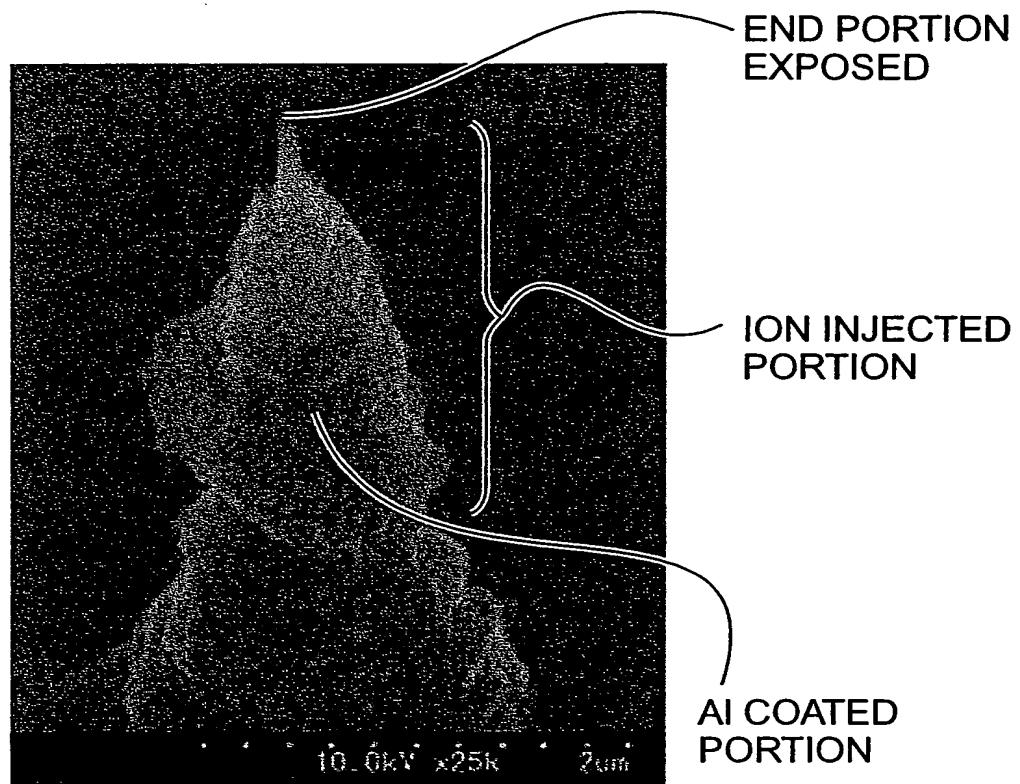
SHARP EMITTER WITH AN AL ELECTRODE

Fig.15



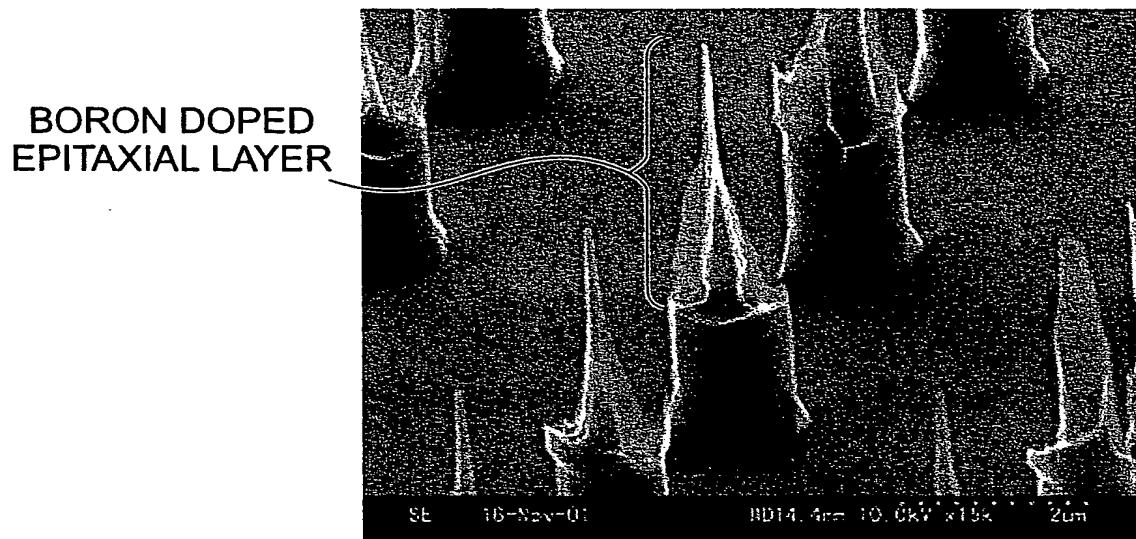
SHARP EMITTER
WITH AN Al ION INJECTED LAYER

Fig.16



PROTRUSION WHERE AN Al ELECTRODE
IS FORMED EXCEPT FOR THE TIP

Fig.17



**SHARP EMITTER INCLUDING
A BORON DOPED EPITAXIAL LAYER**

Fig.18

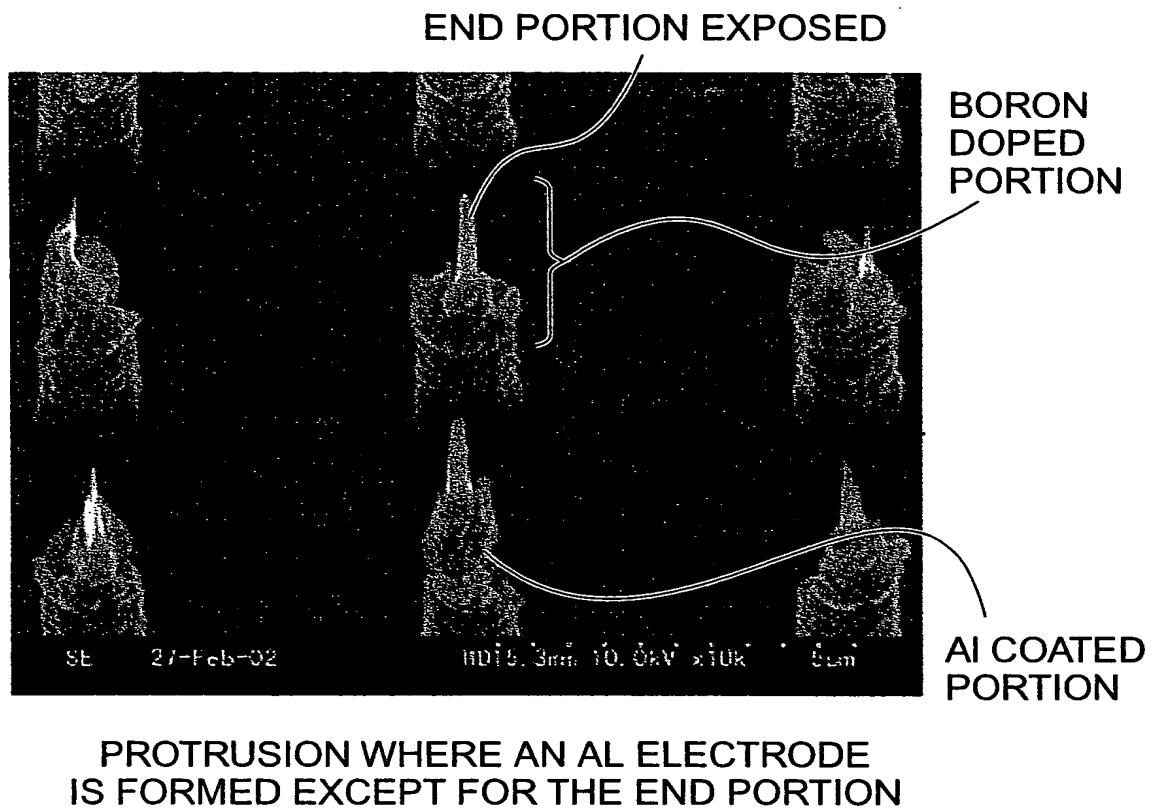
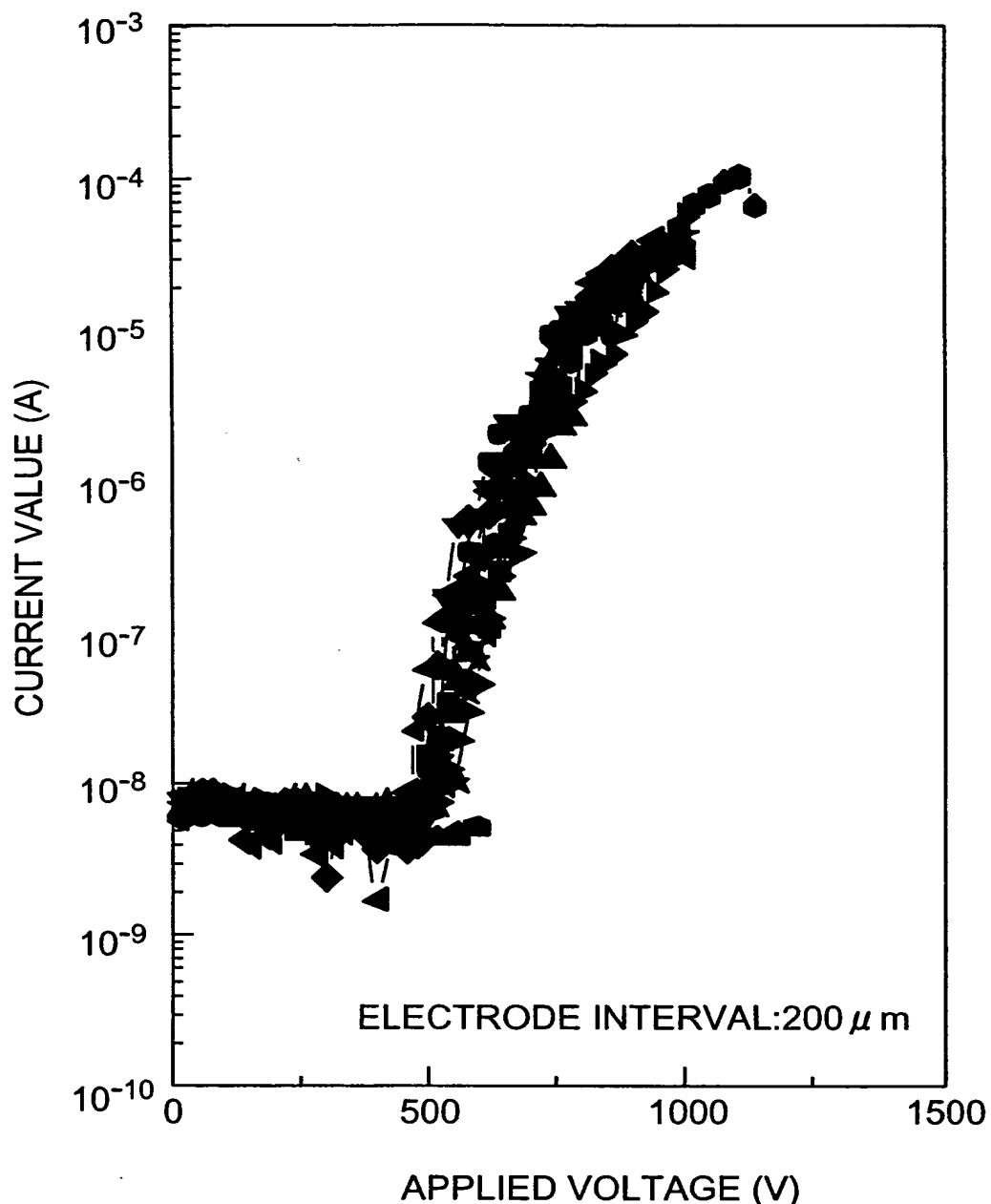
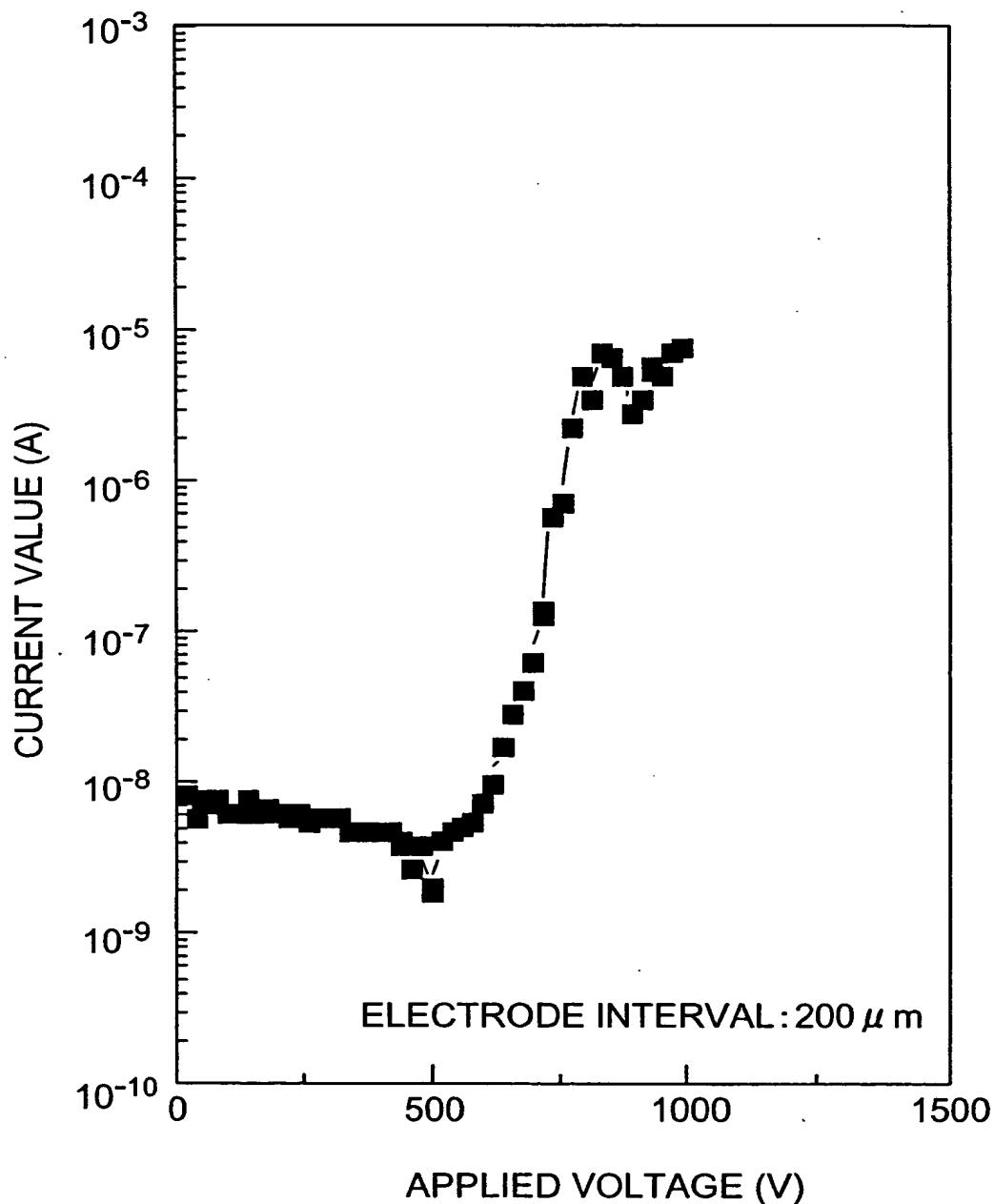


Fig.19

ELECTRON EMISSION CHARACTERISTIC
OF A SHARP EMITTER INCLUDING
AN AI ION INJECTED LAYER
AND BEING PROVIDED WITH AN AI ELECTRODE

Fig.20

ELECTRON EMISSION CHARACTERISTIC
OF A SHARP EMITTER INCLUDING
A BORON DOPED EXITAXIAL LAYER
AND BEING PROVIDED WITH AN AL ELECTRODE